

DAY 1 - 15.05					Chairperson	
13:45	14:15	OPENING REMARKS	Michel de Labachellerie David Gottfried Giancarlo Faini Carlos Ramos	ENRIS, EuroNanoLab & Renatech Tribute to Oliver Brand Presentation of C2N Tribute to Xavier Le Roux		
14:15	15:00	PLENARY 1	Holly Sawyer	Fostering technology transfer and innovation: experiences and lessons learned."		
SESSION 1: Quality and security						
15:00	15:30	INVITED	Flemming Jensen, Jesper Hanberg	Bridging academic research and small-scale production in an open-access nanofabrication facility	Yoshio MITA	
15:30	15:45	Oral1	Thøger Eskildse	Running an ISO 9001 Certified Cleanroom Core Facility		
15:45	16:00	Oral2	Margaret Costa	Pricing Model for Micro and Nanofabrication Services		
16:00	16:15	Oral3	Mariam González Debs	Transitioning to safer and more sustainable fabrication		
16:15	16:30	COFFEE BREAK				
16:30	17:15	PLENARY 2	Hideto Hidaka	Next-generation Novel Integrated Circuits Centers (X-nics) Program in Japan		
SESSION 2: Management of Human & Technical resources - 1						
17:15	17:30	Oral1	Hugo Cortez	Ensuring Reliable and Sustainable Electricity Supply for Micro and Nanofabrication Facilities	Vittorio MORANDI	
17:30	17:45	Oral2	Hugues Granier	Clean room engineers' exchanges: a win/win international collaboration		
17:45	18:00	Oral3	Shun Yasunaga	Chip or Wafer – Small quantity fabrication		
18:00	18:15	Oral4	Leif S. Johansen	3D cleanroom recording for enhanced cleanroom learning		
DAY 2 - 16.05						
9:00	9:45	PLENARY 3	Jane Fitzpatrick	How to network nanofab capabilities - an Australian experience	Anna RISSANEN	
9:45	10:15	INVITED	Jürgen Brugger	Thermal scanning probe lithography (t-SPL) and nanopatterning of 2D material		
SESSION 3: Facility design & Information systems - 1						
10:15	10:30	Oral1	Thøger Eskildsen	DTU Nanolab – LabManager – an in-house Laboratory Web App		
10:30	10:45	Oral2	A. Laborde	Process management in an academic laboratory: recipe library, data access, monitoring, different tools to be implemented		
10:45	11:00	Oral3	Stefano Zampolli	CAMS: an open-source web application for clean-room process management		
11:00	11:15	Oral4	Dino el Hani	CROSS - Clean Room Support Service		
11:15	11:30	COFFEE BREAK				

SESSION 4: Companies Session					
11:30	11:50	Sentech	Gerd Jungmann	The Role of the ICP Plasma Source PTSA in Advanced Etch and Deposition Processes	Thomas SWAHN Laurent MAZENQ
11:50	12:00	Innodys	Alain Cenne	INNODYS...An European Semiconductor Systems and Components Distribution Company	
12:00	12:10	Heidelberg	Vasilis Theophylaktopoulos	The NanoFrazor, a tool for thermal scanning probe lithography	
12:10	12:30	SPS	Pierrick Four	Thickness measurements on patterned substrates	
12:30	12:50	STS Elionix	Lukas Stampfer	Elionix BODEN Electron Beam Lithography Systems. What is new? What are they good for?	
12:50	13:10	Raith	Viacheslav Vlasenko	RAITH Lithography Solutions for clean room environment	
13:10	13:30	Suss Microtec - Electronmec	Sebastiaan calligarich	How Suss drives innovation	
13:30	14:30	LUNCH			
14:30	15:15	PLENARY 4	Collette Maloney	EU Chip Act and role of (semi) academic cleanrooms in ramping up chip production in Europe	Jörg HÜBNER
SESSION 5: Management of Human & Technical resource - 2					
15:15	15:45	INVITED	Peter Modh, Johan Andersson	Energy Savings – One Approach	
15:45	16:00	Oral5	Granier Hugues	Optimization of the energy consumption of the LAAS-CNRS micro and nanotechnologies platform	
16:00	16:15	Oral6	Gerard de Luca	Specialty gases distribution in laboratories – Good practices	
16:15	16:30	Oral7	Leif S. Johansen	Energy savings in cleanroom operations	
16:30	16:45	Oral8	Jesper Hanber	Unleashing Digital Learning for Cleanrooms	
16:45	17:00	COFFEE BREAK			
SESSION 6: Facility design & Information systems - 2					Nils NORDELL
17:00	17:15	Oral5	Stéphane Guilet	DigiClear, a multi-function logbook and managing tool: from machines to samples and projects history.	
17:15	17:30	Oral6	Peter Modh	Myfab LIMS	
17:30	17:45	Oral7	David Gottfried	Metrics and impact measurement of shared User Facilities: lessons from the NNCI	
17:45	18:00	Oral8	Etienne Laligant	Considering vibration challenges when designing a nanoscience facility	
POSTER SESSION					
18:00	19:00	Poster session			
DAY 3 - 17.05					
9:00	9:45	PLENARY 5	Trevor Thornton	Chips Act in US	
SESSION 7: Processes					

9:45	10:00	Oral1	Ayako Mizushima	Long-Term Freestanding Wrinkle-Less SiO ₂ Membrane by Stress-Controlled CVD and Subsequent Annealing Treatment	Frank DIRNE
10:00	10:15	Oral2	Naonobu Shimamoto	Micron-to-Submicron Cu electroplating in view of Agile-X LSI Chips Fabrication using Open Facility	
10:15	10:30	Oral3	Etsuko Ota	Technology transfer of supercritical fluid deposition technology from research group to use in open nanotechnology facilities	
10:30	10:45	Oral4	Mariusz Martyniuk	ANFF-WA: Uniquely providing the merger of MEMS with MBE-grown HgCdTe-based IR imaging complemented with next-generation functionalities	
10:45	11:00	Oral5	Carlos Alonso Ramos	Enabling advanced silicon photonics devices by process optimization	
11:00	11:15	Oral6	Jean-Louis Leclercq	Chitosan as a water-based biosourced photoresist for DUV lithography : from lab- to pilot 300 mm line- scale	
11:15	11:30	COFFEE BREAK			
SESSION 8: Data management					
11:30	12:00	INVITED	Barend Mons	The FAIR approach and its possible use for nanofabrication data	Michal URBANEK
12:00	12:30	INVITED	Mary Tang	Data ecosystems in nanolabs	
SESSION 9: Access, Cooperation & industrial transfer - 1					
12:30	13:00	INVITED	Nadezda Kuznetsova, Michel de Cooman, Frederik Ceyssens, Rik van Daal and Michael Kraft	Important aspects of university cleanroom operation	David GOTTFRIED
13:00	13:15	Oral1	Noriko Kawai	Co-operation of Fablab and Super Clean Room with a big number of users: advantages and challenges.	
13:15	13:30	Oral2	Yukinori Ochiai	Advanced Research Infrastructure for Materials and Nanotechnology (ARIM) at The University of Tokyo	
13:30	14:30	LUNCH			
SESSION 10: Access, Cooperation & industrial transfer - 2					
14:30	14:45	Oral3	Dmitri Y Petrovykh	ASCENT+ European Nanoelectronics Research Infrastructure	Ausrine BARTASYTE
14:45	15:00	Oral4	Benjamin LECHA	RENATECH-Projects	
15:00	15:15	Oral5	Trevor J. Thornton	A Diamond Foundry Service for High Power DC and RF Integrated Circuits	
15:15	15:30	CLOSING REMARKS			

Access, Cooperation and industrial transfer			
41	Gernot Goll	Supplying Scientists with Sub-100nm Structures and More	
40	Frank Dirne	Photonic integration of III-V semiconductor material devices and on advanced functional materials for photonics and quantum.	
16	Chris Bennett	JWNC Overview & Continuous Improvement Journey	
Facility design & Information systems			
9	Paul M Reyno	Process and Data Monitoring on an EBP5200	
27	Jorg Scholvin	RFID Technology in the Cleanroom: Effortless Tracking of Garments & Broader Application to Fab Operation	
Processes			
8	J. Grant	Nanoscale Si Etch Process Development on the SPTS Rapier DSiE tool and Migration from an Ageing Etch Tool	
3	Tauno Kahro	Preparation and characterization of diffractive optical lenses by grayscale maskless photolithography	
22	Hao Huang	2D Metal covalent organic frameworks towards electrochemical catalysis	